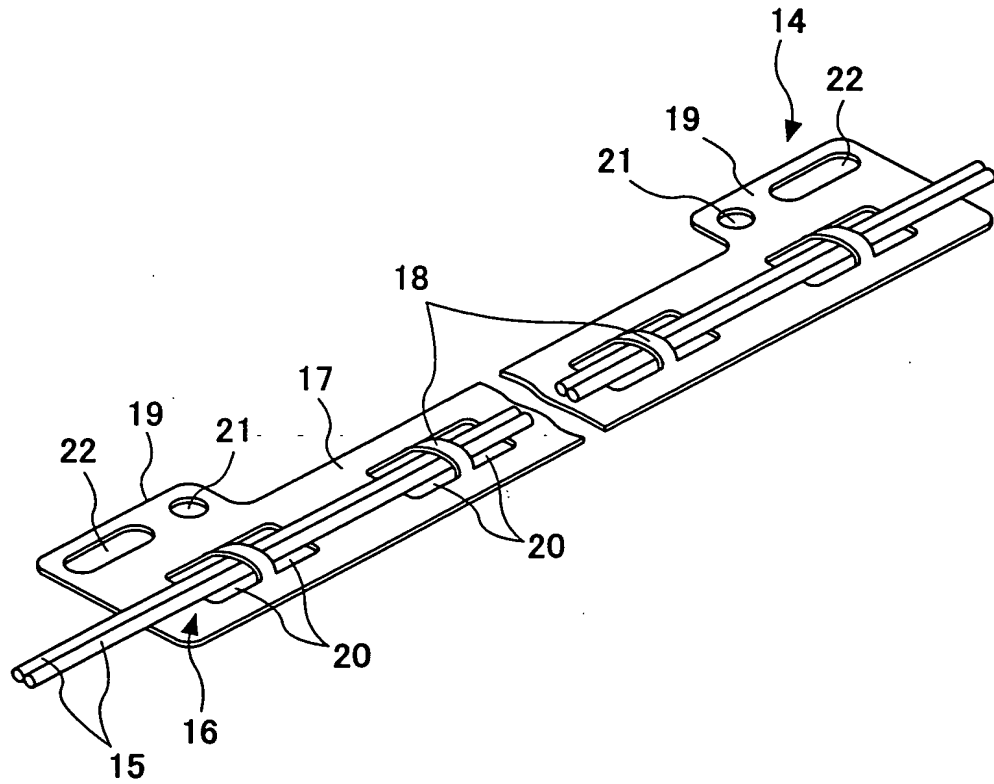


A schematic diagram of a device for measuring the thickness of a material. The device consists of a main body (1) with a top surface (2). A thin layer (3) is positioned on the top surface. A probe (4) is shown in contact with the top surface (2). A dashed line (5) indicates the path of the probe. A component (6) is located below the probe, and a component (7) is located below the probe. A component (8) is located below the probe. A component (9) is located below the probe. A component (10) is located below the probe. A component (11) is located below the probe. A component (12) is located below the probe.

FIG.3



05250" 25249860

FIG.4

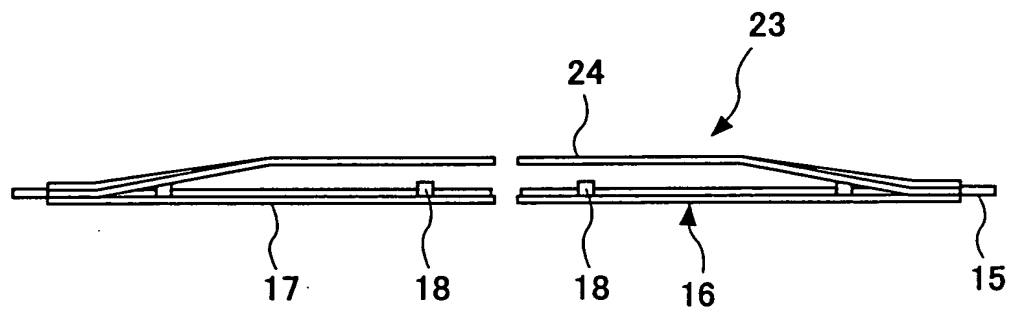


FIG.5

